

ABSTRACT

The present invention is for supplying a specified quantity Q of processing gas while dividing at a desired flow rate ratio Q_1/Q_2 accurately and quickly from a gas supply facility equipped with a flow controller into a chamber. With the present invention, a total quantity $Q=Q_1+Q_2$ of gas while dividing is supplied into a chamber C at a desired flow rate Q_1 and Q_2 through shower plates 3 and 4 fixed to the ends of branch supply lines GL_1 and GL_2 by providing open/close valves OV_1 and OV_2 with a plurality of branch supply lines GL_1 and GL_2 respectively to supply a specified quantity Q of gas G from a gas supply facility 1 equipped with a flow controller QCS into a chamber, and by utilizing a bypass line BL_1 on the downstream side of the afore-mentioned open/close valve OV_1 and branched from GL_1 , a bypass line BL_2 on the downstream side of the open/close valve OV_2 and branched from GL_2 , a pressure type division quantity controller FV connected to the bypass line BL_1 and the bypass line BL_2 , a pressure sensor PS_1 to measure pressure inside the branch supply line GL_1 , and a pressure sensor PS_2 to measure pressure inside the branch supply line GL_2 .